

Title (en)
METHOD AND APPARATUS FOR LOW TEMPERATURE PYROMETRY USEFUL FOR THERMALLY PROCESSING SILICON WAFERS

Title (de)
VERFAHREN UND GERÄT FÜR DIE NIEDERTEMPERATUR-PYROMETRIE, DIE SICH FÜR DIE THERMISCHE BEARBEITUNG VON SILICIUMSCHEIBEN EIGNEN

Title (fr)
PROCEDE ET APPAREIL DE PYROMETRIE A BASSE TEMPERATURE SERVANT AU TRAITEMENT THERMIQUE DE PLAQUETTES DE SILICIUM

Publication
EP 1809111 A4 20101208 (EN)

Application
EP 05814904 A 20051005

Priority

- US 2005036082 W 20051005
- US 97400304 A 20041026

Abstract (en)
[origin: US2006086713A1] A rapid thermal processing (RTP) system including a transmission pyrometer monitoring the temperature dependent absorption of the silicon wafer for radiation from the RTP lamps at a reduced power level. A look-up table is created relating unnormalized values of photodetector photocurrents with wafer and radiant lamp temperatures. A calibrating step measures the photocurrent with known wafer and lamp temperatures and all photocurrents measured thereafter are accordingly normalized. The transmission pyrometer may be used for closed loop control for thermal treatments below 500° C. or used in the pre-heating phase for a higher temperature process including radiation pyrometry in closed loop control. The pre-heating temperature ramp rate may be controlled by measuring the initial ramp rate and readjusting the lamp power accordingly. Radiation and transmission pyrometers may be included in an integrated structure with a beam splitter dividing radiation from the wafer.

IPC 8 full level
F27D 11/00 (2006.01); **G06F 19/00** (2006.01); **H01L 21/205** (2006.01); **H05B 3/68** (2006.01)

CPC (source: EP KR US)
A21B 1/00 (2013.01 - KR); **F27B 5/04** (2013.01 - EP US); **F27B 17/0025** (2013.01 - EP US); **F27D 11/00** (2013.01 - KR); **F27D 21/0014** (2013.01 - EP US); **H01L 21/324** (2013.01 - KR); **H01L 21/67115** (2013.01 - EP US); **H01L 21/67248** (2013.01 - EP US); **H05B 3/68** (2013.01 - EP US)

Citation (search report)

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Designated contracting state (EPC)
DE NL

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US 2006086713 A1 20060427; US 7112763 B2 20060926; CN 101128716 A 20080220; CN 101128716 B 20120905; EP 1809111 A2 20070725; EP 1809111 A4 20101208; JP 2008518472 A 20080529; JP 2012156522 A 20120816; JP 5064227 B2 20121031; JP 5503679 B2 20140528; KR 100885098 B1 20090220; KR 20070060158 A 20070612; WO 2006047062 A2 20060504; WO 2006047062 A3 20070621

DOCDB simple family (application)
US 97400304 A 20041026; CN 200580036894 A 20051005; EP 05814904 A 20051005; JP 2007538953 A 20051005; JP 2012055787 A 20120313; KR 20077010369 A 20070507; US 2005036082 W 20051005